## **Electronic Supplementary Information**

## Bias Stress Stable Aqueous Solution Derived Y-Doped ZnO

## Thin Film Transistors

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**Fig. S1.** XPS spectra of the O1s core level line for the solution processed YZO films as a function of Y content.



Fig. S2. Transfer characteristics of YZO TFTs as a function of Y doping concentration.



**Fig. S3.** (a) Thermogravimetric analysis (TGA) and differential scanning calorimetry (DSC) and (b) thermal behavior as a function of temperature ranging from 200 °C to 500 °C of the as-prepared Y(OH)<sub>3</sub> powder. The numbers in (b) indicate the dehydration percentage for Y(OH)<sub>3</sub>. These valuee were calculated using the ratio of weight loss after 2 h at a specific temperature in (b) to the weight loss at 600 °C (it is considered that a complete dehydration of Y(OH)<sub>3</sub> occurs at600 °C as shown in in (a)).



**Fig. S4.** Thermogravimetric analysis (TGA) and differential scanning calorimetry (DSC) of Zn(OH)<sub>2</sub> powder.



**Fig. S5.** (a) XRD patterns of ZnO and YZO films deposited on silicon substrate. Film thickness was ~ 150 nm. (b) Representative SEM top-view images of ZnO and YZO films as a function of Y doping concentration. Scale bar = 100 nm.



Fig. S6. The  $\sqrt{I_D}$  vs  $V_G$  plot to extract the threshold voltage shift for the spin-coated YZO-TFTs fabricated on SiO<sub>2</sub>/n<sup>+</sup>-Si substrates as a function of Y doped ratio. (a) and (b) samples were annealed at 300 °C. (c) and (d) samples were annealed at 250 °C. The bias instability was analyzed under a positive bias stress.